## COURSE GUIDE - short form

Academic year 2021-2022

Course name <sup>1</sup>	Vacuum deposition techniques II				Cour	MATAE I 107			
Course type <sup>2</sup>	DS	Category <sup>3</sup>	DI	Year of study	V	Semester	2	Number of credit points	6

Faculty	Materials Science and Engineering		Number of teaching and learning hours <sup>4</sup>						
Field	Materials engineering	Total	L	Т	LB	Р	IS		
Specialization	Advanced materials and experimental analysis techniques	42	28		14				

Pre-requisites from the	Compulsory	-
curriculum <sup>5</sup>	Recommended	Vacuum deposition techniques I

General objective <sup>6</sup>	Acquiring and appropriate use of concepts and methods of making thin films deposited in vacuum
Specific objectives <sup>7</sup>	Work Skills Training facility vacuum deposition, magnetron booked and evaporation; Gaining theoretical and practical methods, procedures and devices usual deposition of thin films; Gaining theoretical and practical methods and means of characterization of thin films deposited in vacuum; Identify applications of thin layers deposited by physical methods;
Course description <sup>8</sup>	Methods, procedures and devices in vacuum thermal evaporation deposition; Methods, procedures and devices Sputter deposition; Ion plating deposition methods; Methods for chemical vapor deposition at low pressure; Monitoring and control of thin film vacuum deposition; Methods and means of surface analysis to determine the composition deposited layers; Methods and means for determining the structure of thin films deposited in vacuum; Methods and means for determining the thickness of thin films deposited in vacuum; Methods and means for determining adherence deposited layers; Methods and means for determining the corrosion resistance of the deposited layers; Applications of thin films deposited in vacuum by means of physical, chemical and physicochemical;

	Sche- dule <sup>9</sup>	Percentage in the final grade (minimum grade) <sup>10</sup>			
A. Final	Class tests along the semester	20%	Week 8-10		
assessment form <sup>11</sup> :	Home works	%	-	700/ (	
	Other activities	%	-	70% (minimum	
Exam / Colloquium	Examination procedures and conditions: Probe 1: Three subjects with open questions. Working time 100 minutes	50% (mini- mum 5)		5)	
B. Seminar Activity during seminar				% (minimum 5)	
C. Laboratory Activity during laboratory			30% (minimum 5)		
D. Project Activity during project				% (minimum 5)	

Course organizer	Ioan Gabriel SANDU	
Teaching assistants	Ioan Gabriel SANDU	

<sup>&</sup>lt;sup>1</sup>Course name from the curriculum

 $^2$  DF – fundamental, DID – in the field, DS – specialty, DC – complementary (from the curriculum)

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<sup>&</sup>lt;sup>3</sup> DI – imposed, DO –optional, DL – facultative (from the curriculum)

<sup>&</sup>lt;sup>4</sup> Points 3.8, 3.5, 3.6a,b,c, 3.7 from the Course guide – extended form (L-lecture, T-tutorial, LB-laboratory works, P-project, IS-individual study)

<sup>&</sup>lt;sup>5</sup> According to 4.1 – Pre-requisites - from the Course guide – extended form

<sup>&</sup>lt;sup>6</sup> According to 7.1 from the Course guide – extended form

<sup>&</sup>lt;sup>7</sup> According to 7.2 from the Course guide – extended form

<sup>&</sup>lt;sup>8</sup> Short description of the course, according to point 8 from the Course guide – extended form

 $<sup>^9</sup>$  For continuous assessment: weeks 1-14, for final assessment – colloquium: week 14, for final assessment-exam: exam period

<sup>&</sup>lt;sup>10</sup> A minimum grade might be imposed for some assessment stages

<sup>&</sup>lt;sup>11</sup> Exam or colloquium